

10 a motor connected to rotate the end effector about the end effector axis to
11 thereby provide a yaw motion; and
12 means for monitoring and controlling the yaw motion such that the end
13 effector can be moved in a straight line which is not restricted to the radial direction.

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3 31. (Twice Amended) A robotic arm structure providing θ motion and R motion
4 about a primary axis, the arm structure comprising:
5 an end effector for transporting semiconductor substrates attached to the arm
6 structure and being rotatable about an end effector axis;
7 a first motor connected to rotate the end effector about the end effector axis
8 to provide a yaw motion;
9 a second motor connected to rotate the end effector to provide a roll motion
of the end effector; and
means for monitoring and controlling the yaw and roll motions.

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3 35. (Twice Amended) A robotic arm structure providing θ motion and R
4 motion about a primary axis, the arm structure comprising:
5 an end effector for transporting semiconductor substrates attached to the arm
6 structure and being rotatable about an end effector axis;
7 a first motor connected to rotate the end effector about the end effector axis
8 to provide a yaw motion;
9 a second motor connected to rotate the end effector to provide a roll motion
10 of the end effector;
11 a third motor connected to rotate the end effector to provide a pitch motion
of the end effector; and
means for monitoring and controlling the yaw, roll, and pitch motion.

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39. (Twice Amended) A robotic arm structure providing ~~θ~~ motion and R motion about a primary axis, the arm structure comprising:
an end effector for transporting semiconductor substrates attached to the arm structure and being rotatable ~~about an end effector axis~~;
a first motor connected to rotate the end effector about the end effector access to provide a yaw motion;
a second motor connected to rotate the end effector to provide a pitch motion of the end effector; and
means for monitoring and controlling the yaw and pitch motions.

— Please add new Claim 49 and 50 as follows:

8.
--49.
1 (New) The robotic arm structure according to Claim 1, wherein the means
2 for monitoring and controlling the yaw motion moves the end effector in a straight line
3 which extends along a longitudinal axis of the end effector.

1 50. (New) The robotic arm structure according to Claim 1, wherein the means
2 for monitoring and controlling the yaw motion moves the end effector in a straight line and
3 maintains a constant orientation of the end effector.--

REMARKS

Reconsideration and allowance of the above-identified application are respectfully requested. Claims 1-7, 15-19, 31, 35, 39, and 44-48 are currently pending.

Claim 1 has been rejected under 35 U.S.C. §112 as indefinite because there was no right bracket corresponding to the left bracket in line 5 of the amended claim. Claim 1 as amended above clarifies this typographical error.